



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Pan et al.

Serial No.: 09/614,113

Filed: July 12, 2000

For: TECHNIQUE FOR ELIMINATION OF PITTING ON SILICON SUBSTRATE

DURING GATE STACK ETCH

Confirmation No.: 1710

Examiner: C. Brown

Group Art Unit: 1765

Attorney Docket No.: 2915.3US

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CERTIFICATE OF MAILING

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Sir:

In accordance with 37 C.F.R. § 1.34(b), please recognize the following individual as an associate agent/attorney herein in connection with the above-identified patent application, and with all continuing and divisional applications hereof:

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